



# Development of new ionization chamber specialized in high- $Z$ beam

Masahiro Yoshimoto

BigRIPS Team, RIKEN Nishina Center

Authors:

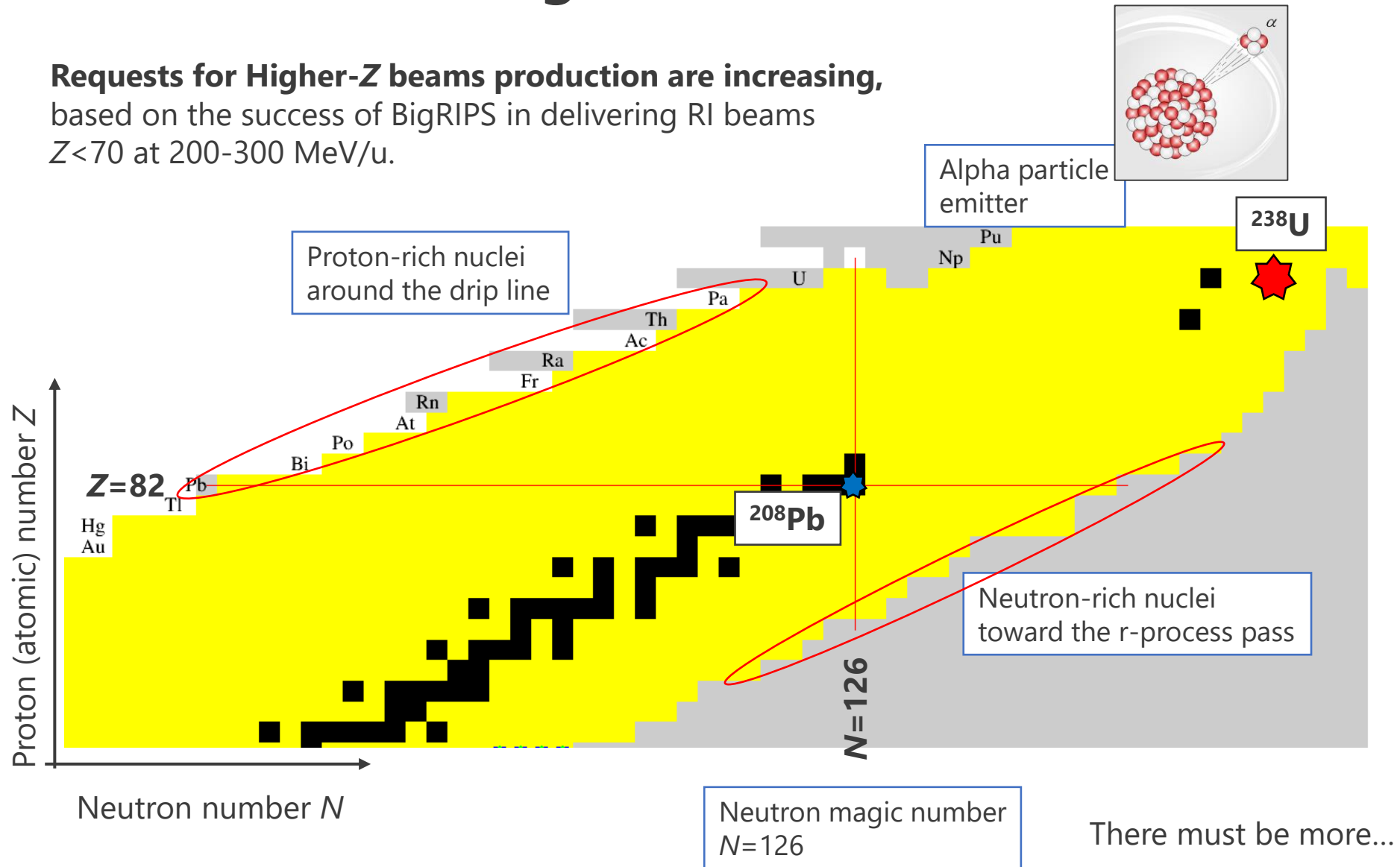
M. Yoshimoto, N. Fukuda, H. Otsu, Y. Shimizu, T. Sumikama, H. Suzuki, H. Takeda, J. Tanaka, K. Yoshida (RIKEN Nishina Center),  
R. Matsumura (Saitama Univ.),  
D. Nishimura, H. Takahashi (Tokyo City Univ.)

# Outline

- Introduction
  - Motivation for high-Z beam @ RIBF
  - BigRIPS separator & in-flight PID
  - Issues for high-Z beam
  - Charge-state fluctuation
- Experiment
  - New Xenon gas IC
  - Primary beam exposure
  - Secondary beam exposure
- Results
- Summary

# Motivation for high- $Z$ beam @ RIBF

**Requests for Higher- $Z$  beams production are increasing,**  
based on the success of BigRIPS in delivering RI beams  
 $Z < 70$  at 200-300 MeV/u.



# BigRIPS separator & in-flight PID

TOF- $B\rho$ - $\Delta E$  method

$$\frac{A}{Q} = \frac{B\rho c}{\beta\gamma m_u}$$

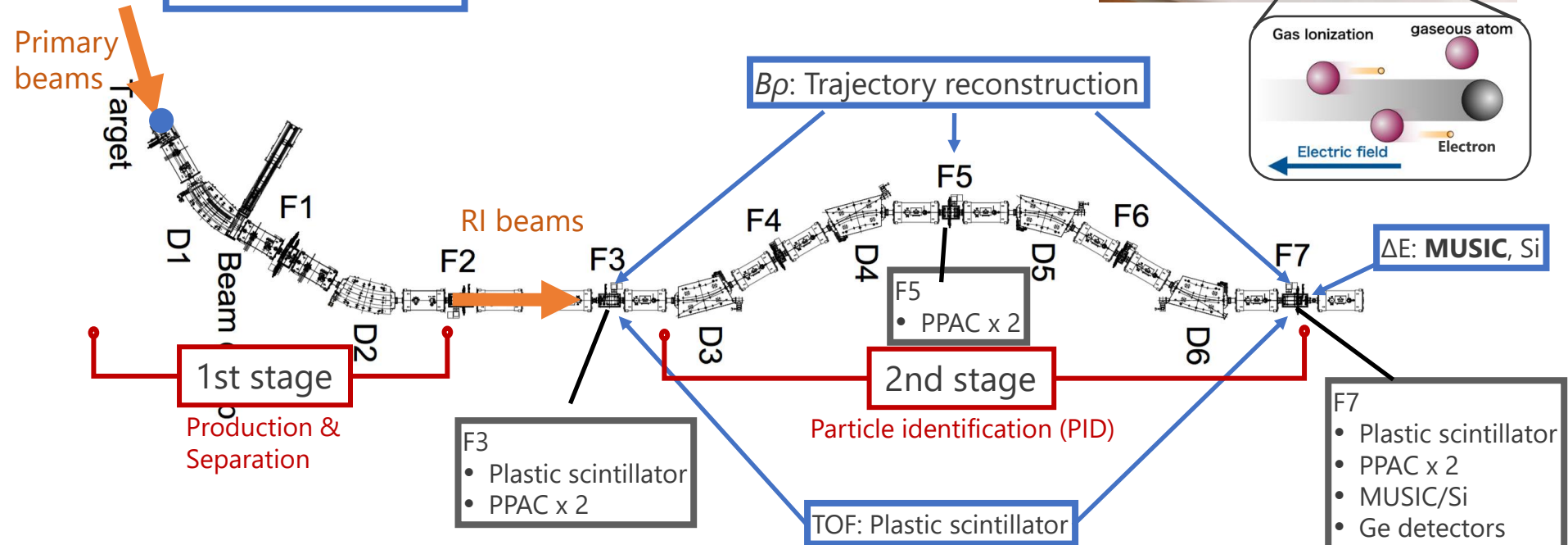
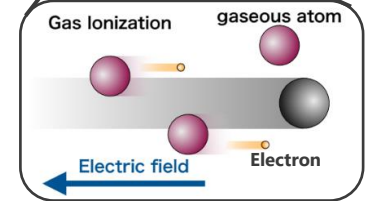
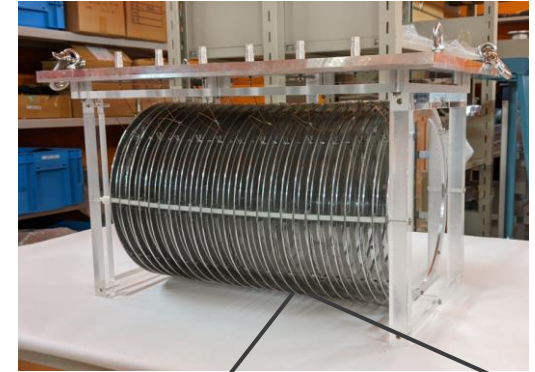
$$Z \leftarrow \Delta E = f(Z, \beta)$$

$B\rho$  : magnetic rigidity

TOF: time of flight

$\Delta E$  : energy loss

## MUSIC: Multi-Sampling Ionization chamber



Parallel Plate Avalanche Counter (PPAC)



Plastic scintillation counter

Previous studies on MUSIC

W. B. Christie, *et al.* NIM A **255**, 466–476 (1987).

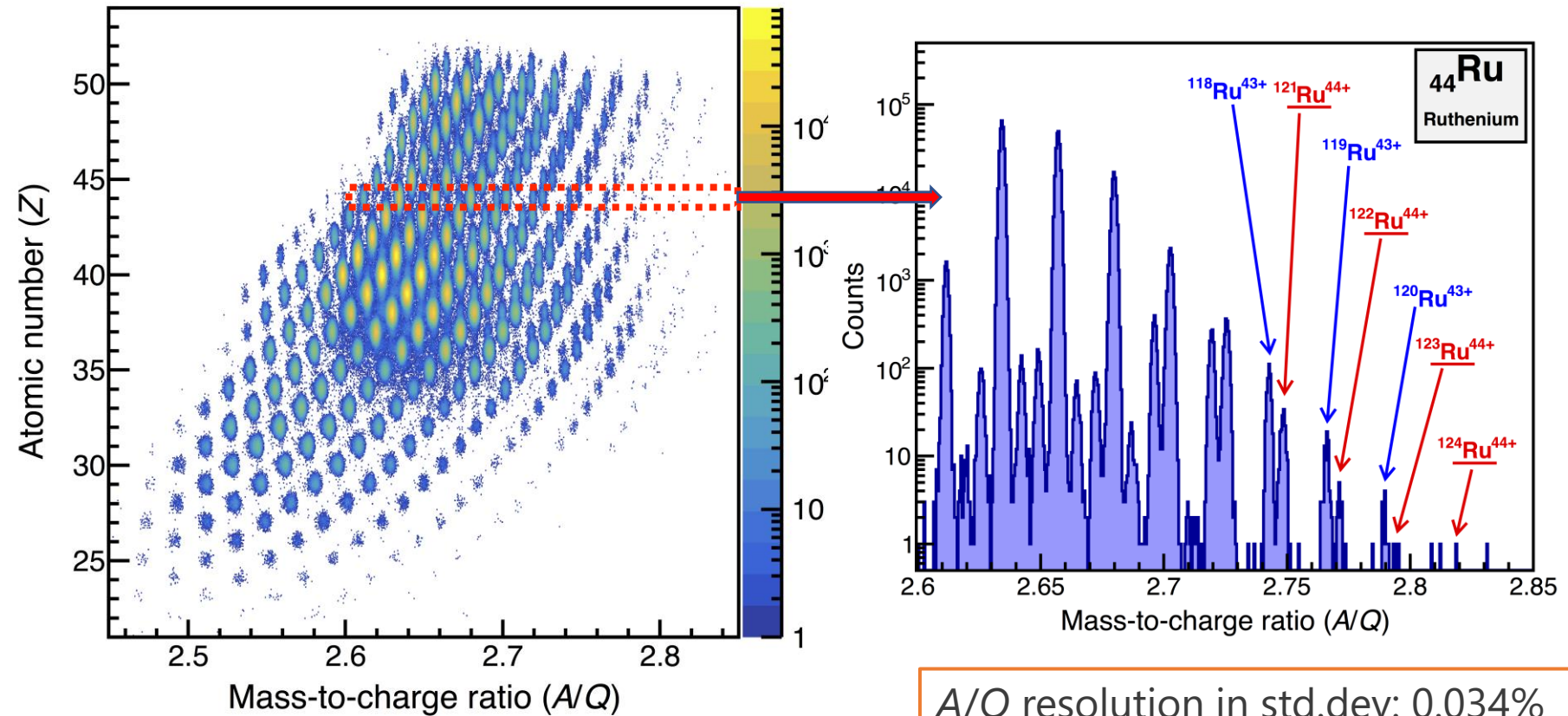
M. Pfützner, *et al.* NIM B **86**, 213–218 (1994).

K. Kimura, *et al.* NIM A **538**, 608–614 (2005).

Y. Sato, *et al.* Jpn. J. Appl. Phys. **53**, 016401 (2014).

# BigRIPS separator & in-flight PID

$^{238}\text{U}$  (345 MeV/u) + Be (2.9 mm<sup>t</sup>),  $B\rho = 7.990$  Tm



$A/Q$  resolution in std.dev: 0.034%  
→  $6.1\sigma$  separation

N.Fukuda *et al.*, Nucl. Instrum. Meth. B 317, 323 (2013)

# Issues for high-Z beam

Poor **Z resolution** of ionization chamber at F7 in high-Z region at 200-300 MeV/u\* has been a major problem so far.

Why is the Z resolution so poor for the high-Z beams at this energy?

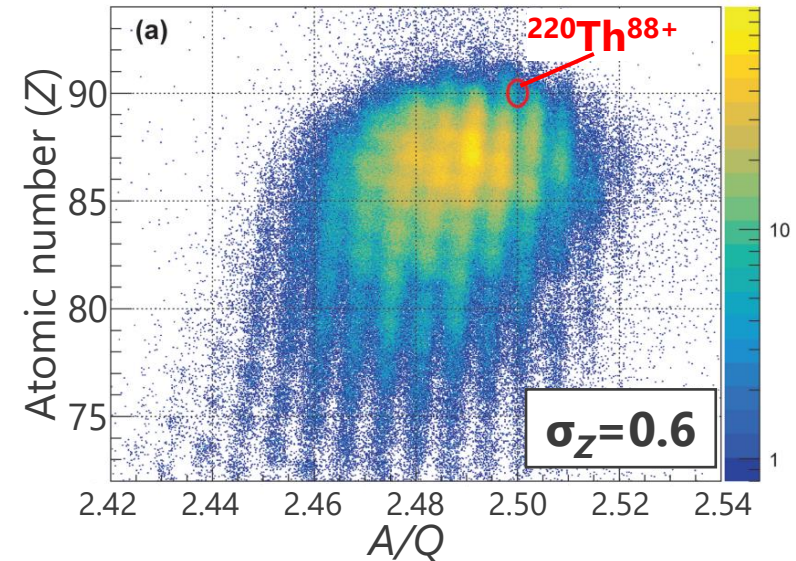
→ Charge-state (Q) fluctuation

- Electron capture and electron stripping occurs in material with heavy ions
- Changing effective Z in IC changes  $\Delta E$
- H. Weick, *et al.* Phys. Rev. Lett. **85**, 2725 (2000).

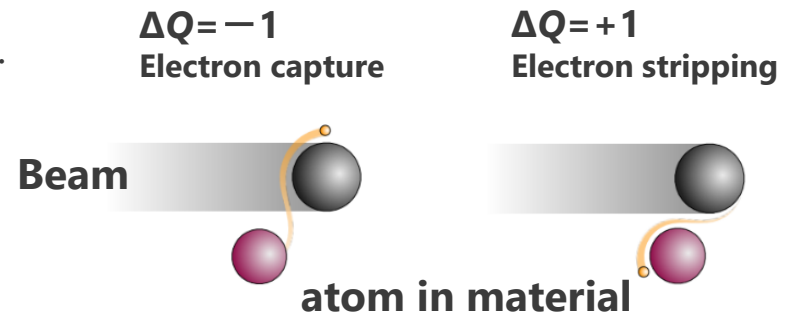
Z considering Q fluctuation

$$\Delta E \propto \frac{Z_{eff}^2}{\beta^2} \left[ \ln \frac{2m_e(\beta c)^2}{I} - \ln(1 - \beta^2) - \beta^2 \right]$$

High-energy high-Z beam production  
 $^{216}\text{Th}$  and  $^{220}\text{Th}$  ( $Z=90$ )  $\geq 250$  MeV/u



$^{238}\text{U}$  primary beam, Be 1mm target, No degraders  
 RIKEN Accel. Prog. Rep. 54 (2021)

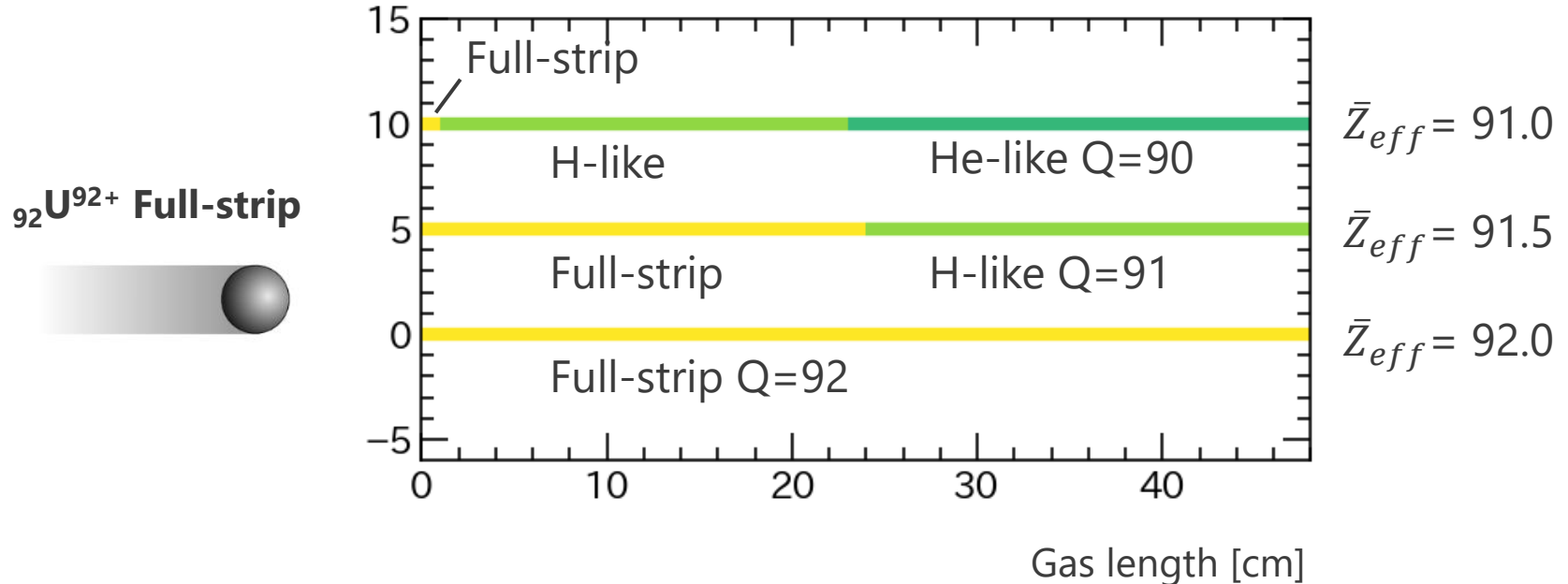


\* Results for other energy and charge states  
 $\sigma_Z=0.24$  @  $Z=92$  500 MeV/u F. Farinon, PhD thesis, Justus Liebig University Giessen (2011).  
 $\sigma_Z=0.4$  @  $Z=88$  180 MeV/u T. Sumikama, *et al.* NIM B **463**, 237 (2020). 6

# Charge-state fluctuation

$$\bar{Z}_{eff} = \frac{\overbrace{Q_0 \sum L_{Q_0}}^{\text{Full-strip}} + \overbrace{Q_1 \sum L_{Q_1}}^{\text{H-like}} + \overbrace{Q_2 \sum L_{Q_2}}^{\text{He-like}}}{\text{Gas length}}$$

in ionization chamber



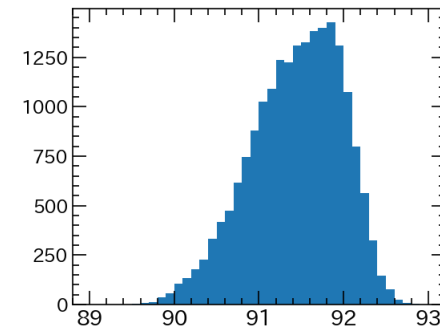
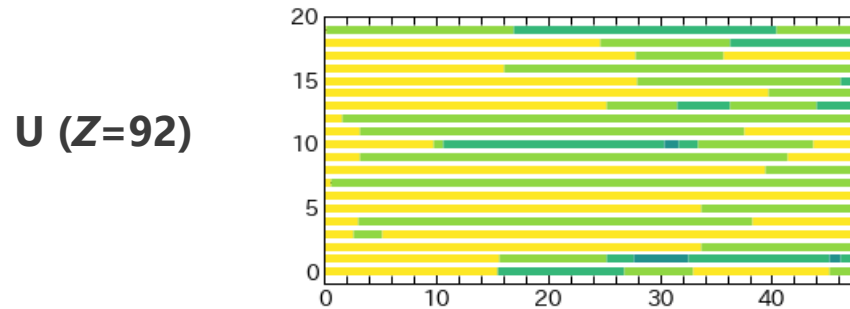
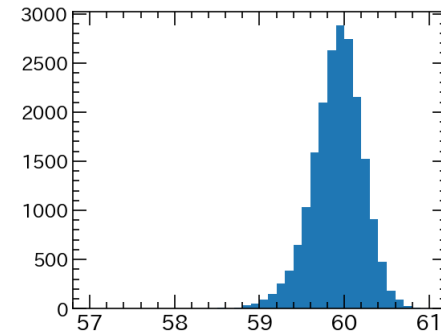
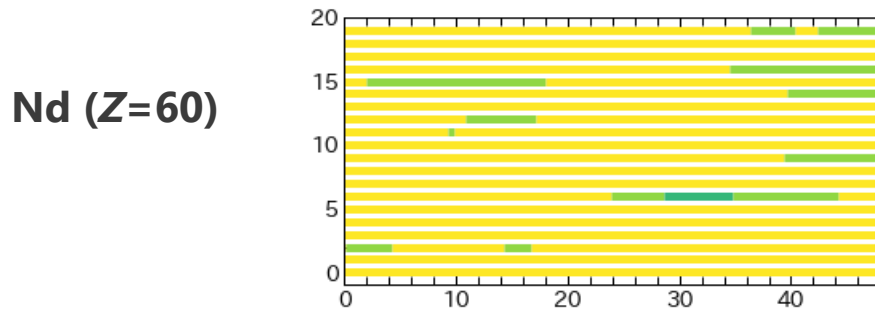
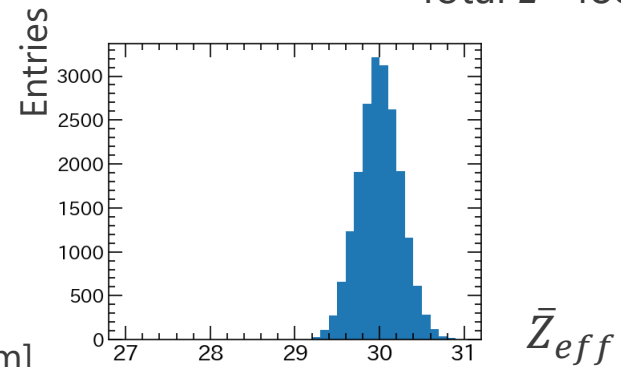
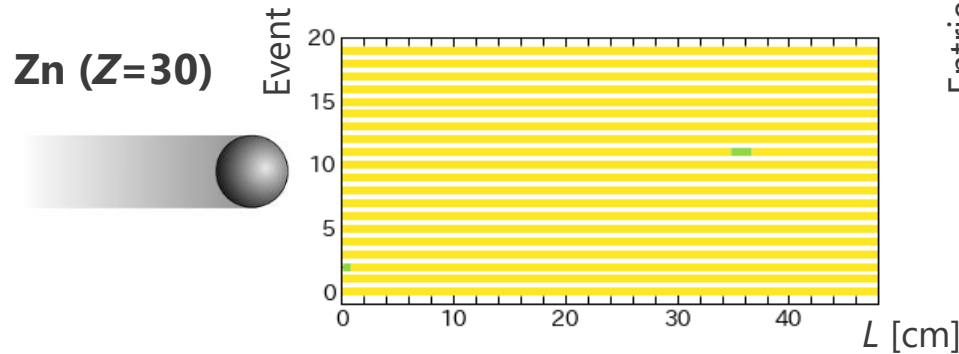
# Charge-state fluctuation

**P10 gas**

Argon 90%  
Methane 10%  
0.8 atom,  
Total  $L=48\text{cm}$

300 MeV/u  
Full-strip

$$\bar{Z}_{eff} = \frac{Q_0 \sum L_{Q_0} + Q_1 \sum L_{Q_1} + Q_2 \sum L_{Q_2}}{\text{Gas length}}$$





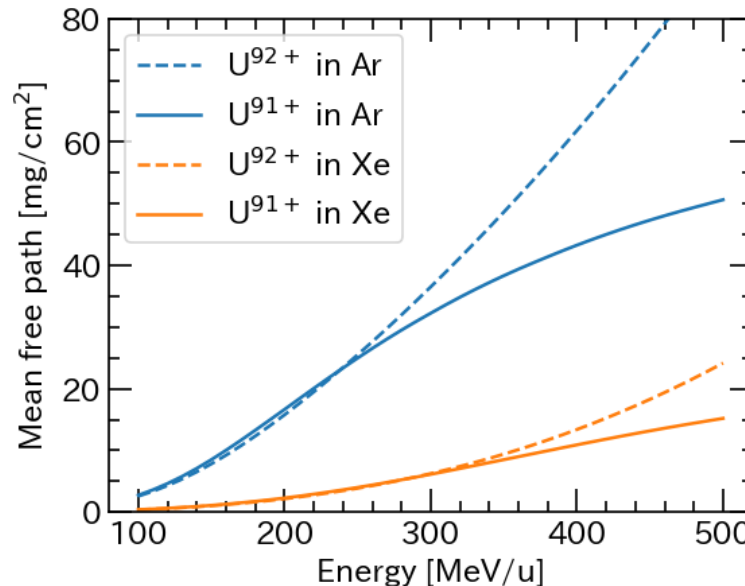
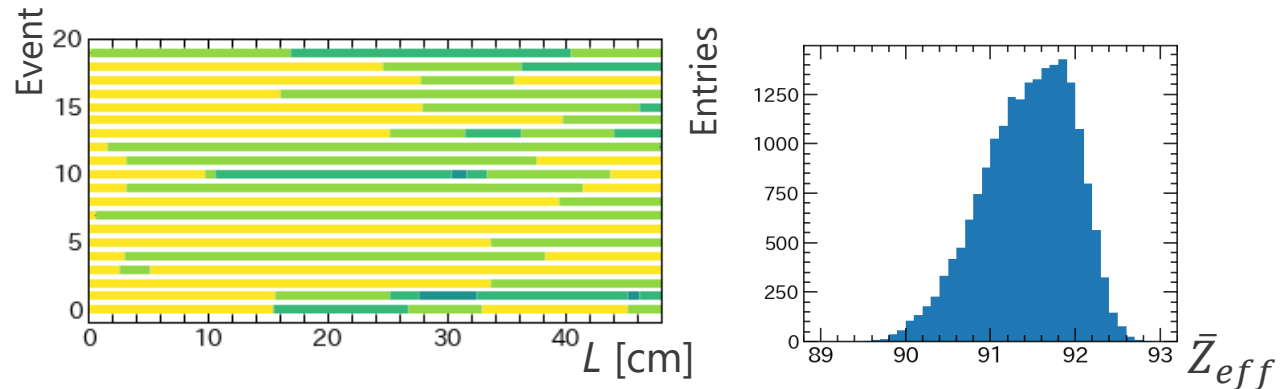
# Charge-state fluctuation

300 MeV/u  
Full-strip

U (Z=92) beam

**P10 gas**

$$\bar{Z}_{eff} = \frac{\overbrace{Q_0 \sum L_{Q_0}}^{\text{Full-strip}} + \overbrace{Q_1 \sum L_{Q_1}}^{\text{H-like}} + \overbrace{Q_2 \sum L_{Q_2}}^{\text{He-like}}}{\text{Gas length}}$$



**Argon**



**Xenon**

# Charge-state fluctuation

300 MeV/u  
Full-strip

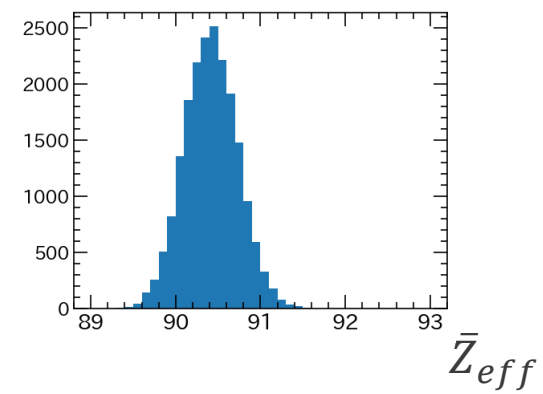
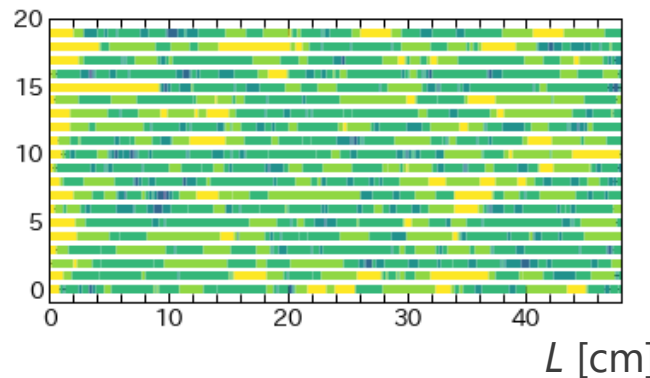
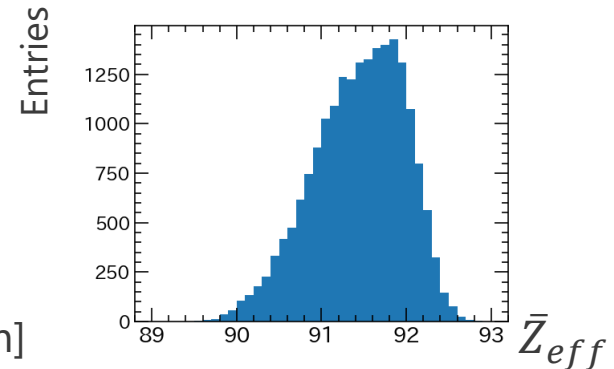
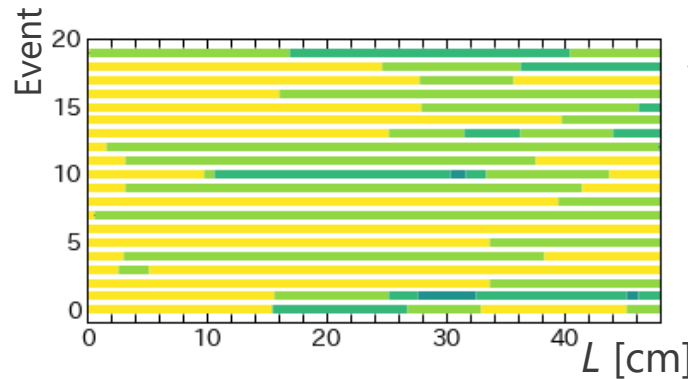
$$\bar{Z}_{eff} = \frac{\overbrace{Q_0 \sum L_{Q_0}}^{\text{Full-strip}} + \overbrace{Q_1 \sum L_{Q_1}}^{\text{H-like}} + \overbrace{Q_2 \sum L_{Q_2}}^{\text{He-like}}}{\text{Gas length}}$$

U (Z=92) beam

**P10 gas**



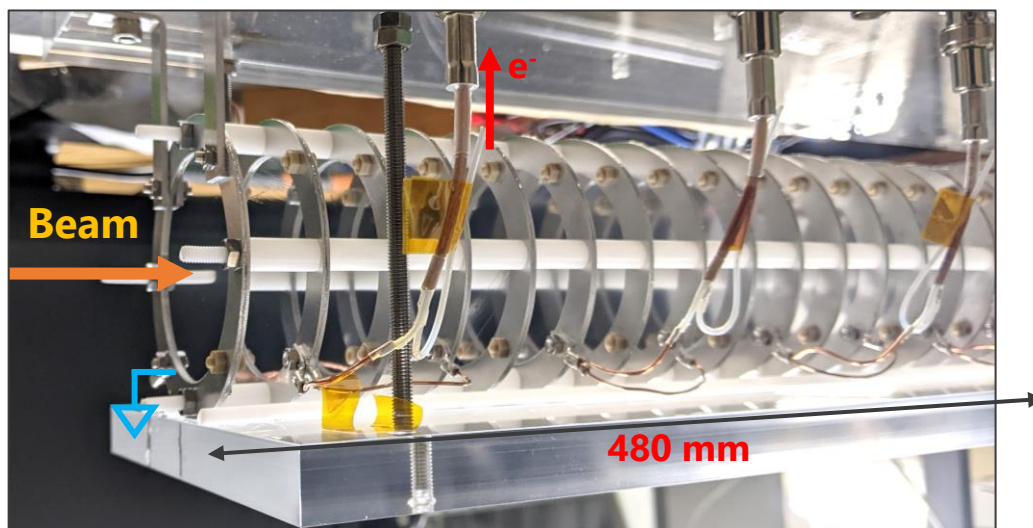
**Xenon gas**



**Xenon gas is promising** for ionization chamber for high-Z beam.

# Xenon gas IC

Electrode:  $\phi 60$  mm x25  
placed at 2cm intervals



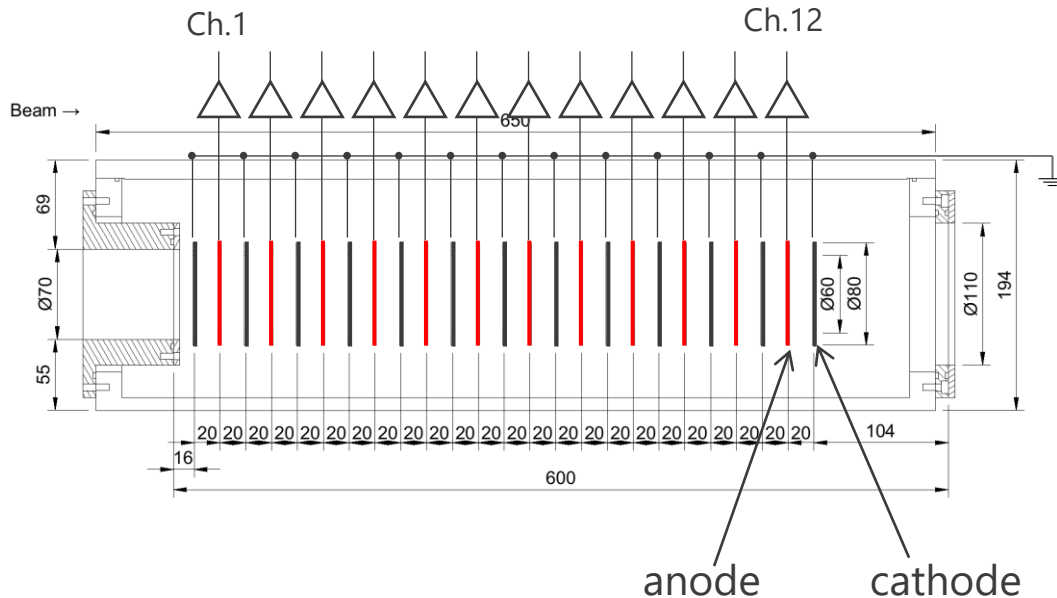
| IC type                                      | Argon-based (P10)                       | Xenon-based                             |
|----------------------------------------------|-----------------------------------------|-----------------------------------------|
| Mixture                                      | <b>Argon 90%</b><br>CH <sub>4</sub> 10% | <b>Xenon 70%</b><br>CH <sub>4</sub> 30% |
| High voltage [V]                             | 400                                     | 800                                     |
| Electron drift velocity<br>$W$ [cm/ $\mu$ s] | <b>4.9</b><br>Computed with             | <b>3.5</b><br>Garfield++                |
| Gas flow                                     | Yes                                     | No                                      |
| Pressure [Torr]                              | 620                                     | 620                                     |
| Total gas thickness<br>[mg/cm <sup>2</sup> ] | 76.5                                    | 198                                     |

Mixed methane to increase electron drift velocity

Xenon is expensive, so IC was operated in containment.

This increase corresponds to Be 0.4 mm<sup>t</sup>.

# IC data acquisition



## Electronics

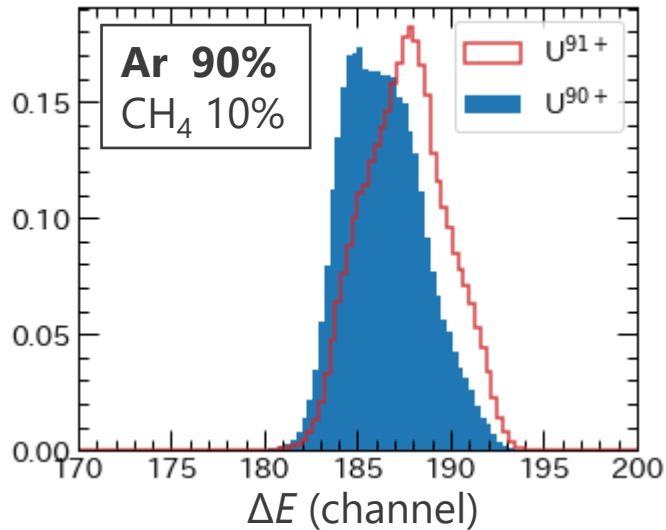
1. Pre amp.  
Mesytec MPRT-16-HV  
Decay time 7  $\mu$ s
2. Shaping amp.  
Mesytec MSCF-16  
Shaping time 1  $\mu$ s
3. ADC  
Technoland T-CM405

## Data processing

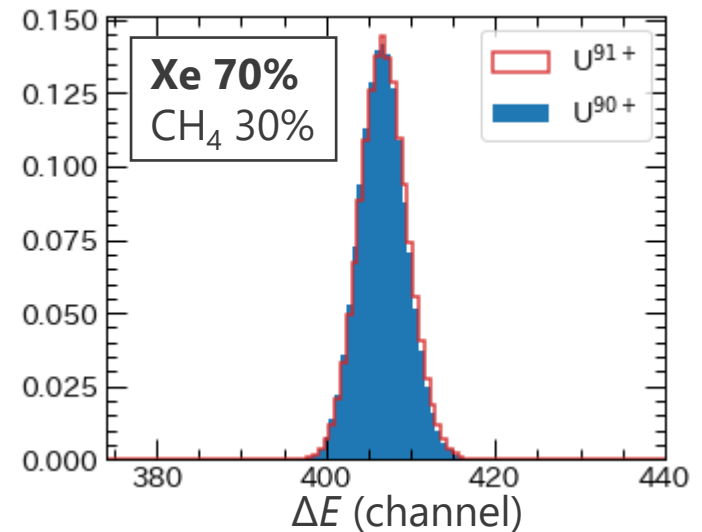
4. Pedestal and gain correction
5. Geometric mean  $^{12}\sqrt{\Pi ADC_{Ch.}}$
6. IC positional correction
7. Velocity  $\beta$  correction with simple Bethe formula and empirical correction.

# Primary beam

He-, H-like  
 $^{238}\text{U}^{90+,91+}$  344 MeV/u beam  
 $\sigma_E$ : less than 0.1%



Q=91+  $187.5 \pm 2.1$  (**1.13%**)  
90+  $186.5 \pm 2.0$  (**1.09%**)



Q=91+  $406.8 \pm 2.8$  (**0.69%**)  
90+  $406.7 \pm 2.8$  (**0.69%**)

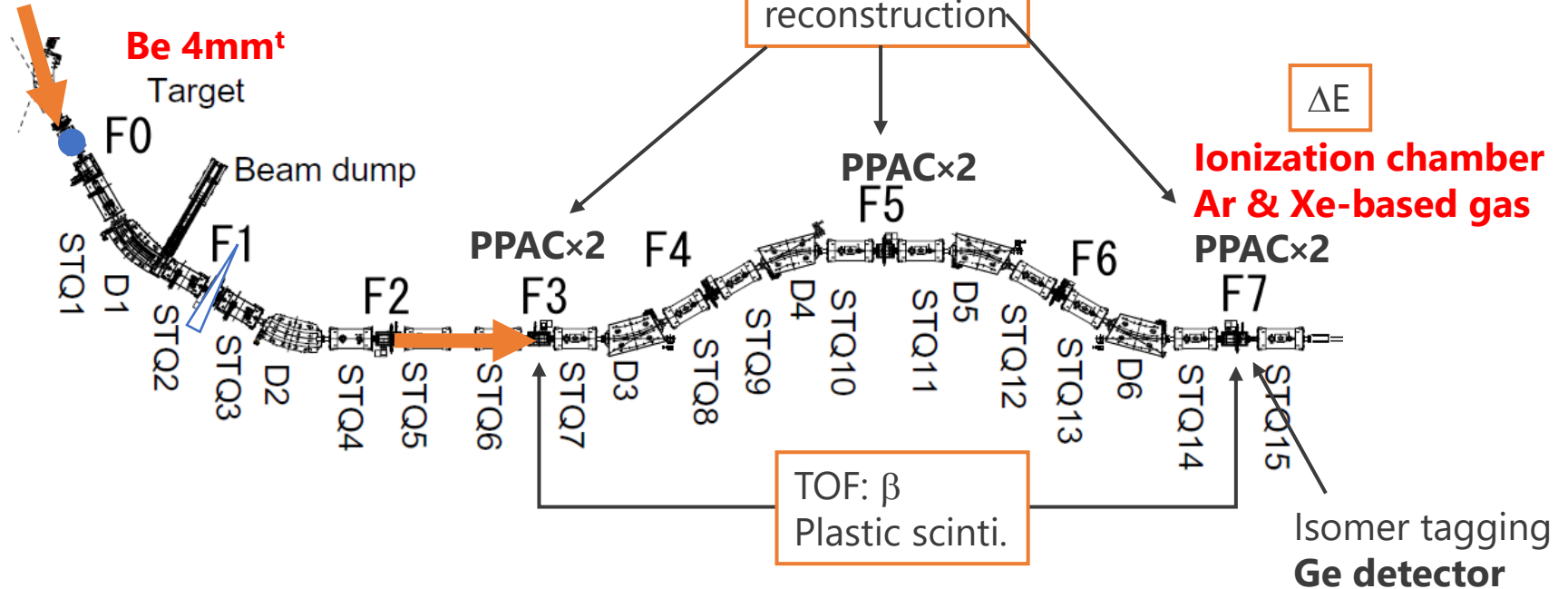
No charge-state dependence and narrow  $\Delta E$  distribution was confirmed with the Xe gas IC.

# Secondary beam

TOF-B $\rho$ - $\Delta E$  method

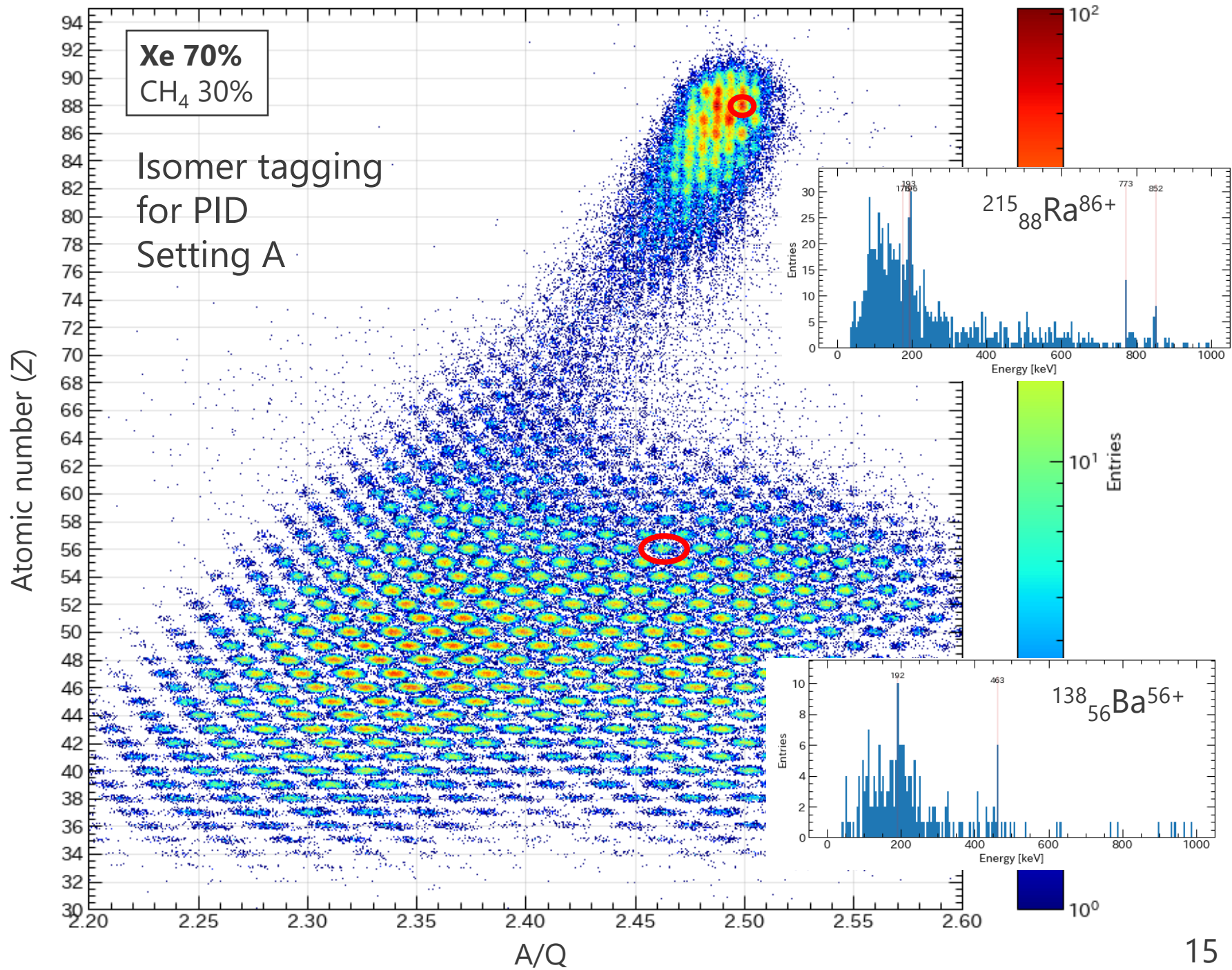
Primary beam  
 $^{238}\text{U}^{86+}$  345 MeV/u

TOF: Time of flight  
B $\rho$  : Magnetic rigidity  
 $\Delta E$  : Energy loss



|            | Setting A                                   | Setting B                                   |
|------------|---------------------------------------------|---------------------------------------------|
| Energy @F7 | 280 MeV/u @ Z=50<br><b>260 MeV/u @ Z=85</b> | 240 MeV/u @ Z=50<br><b>200 MeV/u @ Z=85</b> |
| D1         | 6.3 Tm                                      | 6.1712 Tm                                   |
| F1         | No degrader                                 | Al 2mm degrader<br><b>for Z separation</b>  |

Beam intensity:  
1 kcps @F7

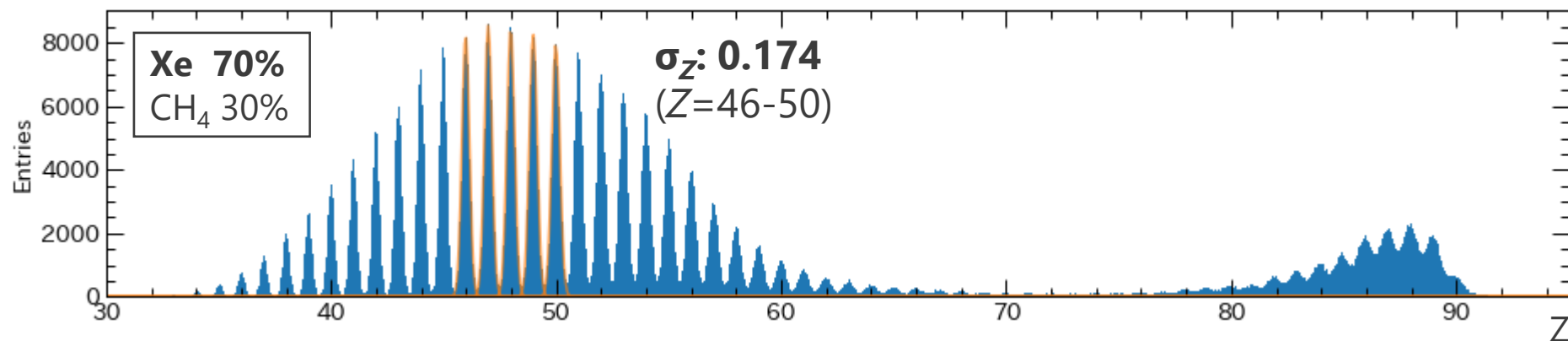
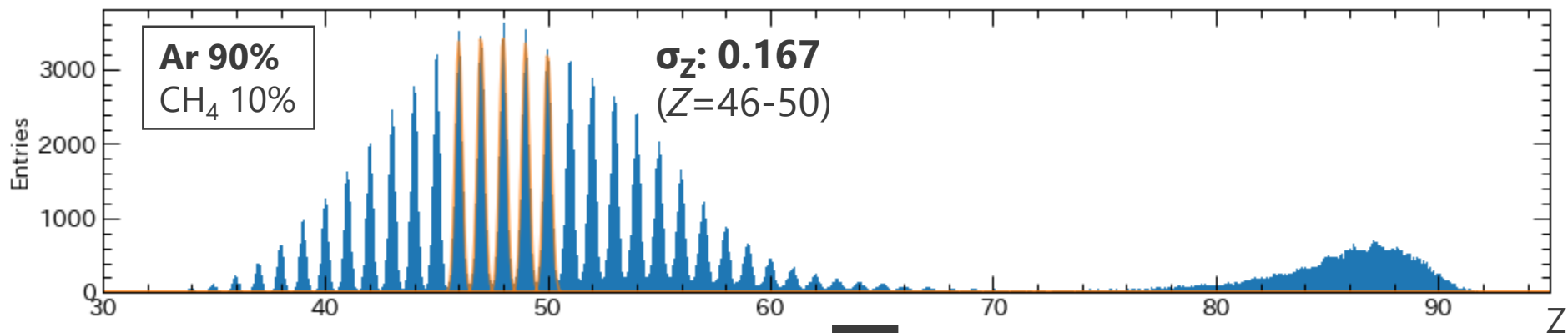




## Setting A

280 MeV/u @  $Z=50$

260 MeV/u @  $Z=85$

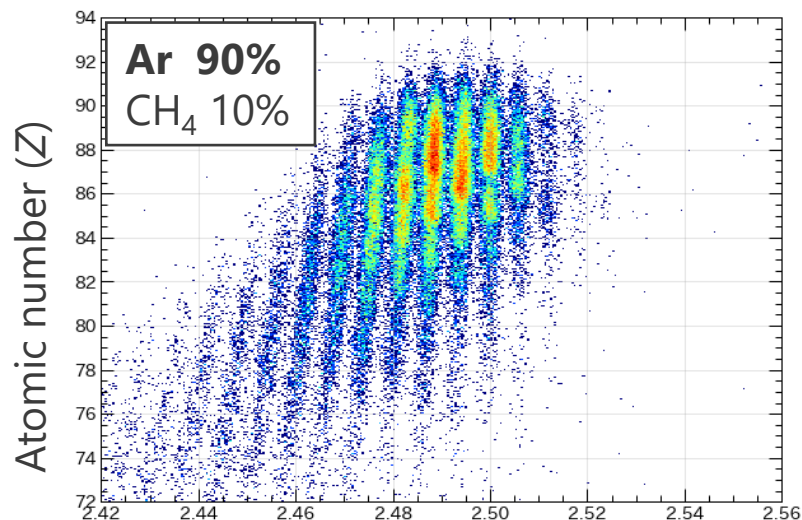


No difference in Z resolution at  $Z=30-60$  between Ar and Xe gas ICs.

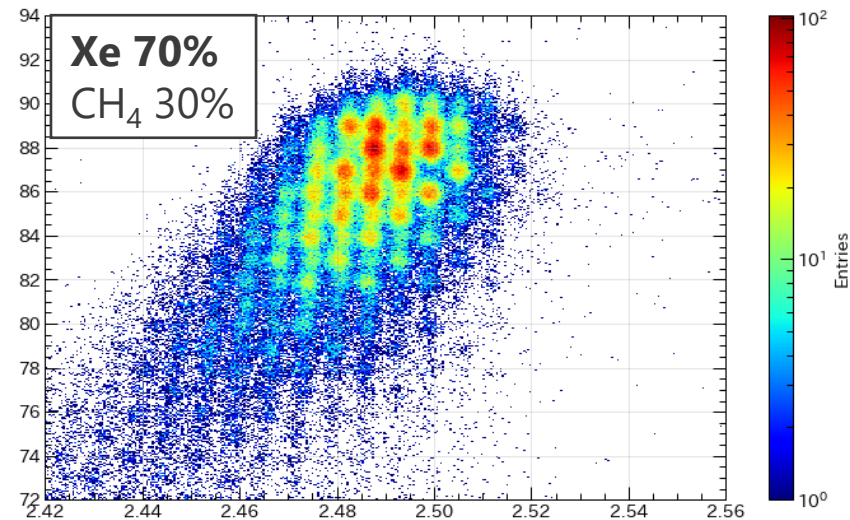
Big difference at  $Z > 80$ .  
Z is not separated in Ar gas IC,  
whereas separated in Xe gas IC.



In the  $Z > 80$  region, **H-like** and **He-like** are transported, so the blobs of the ions are dense.

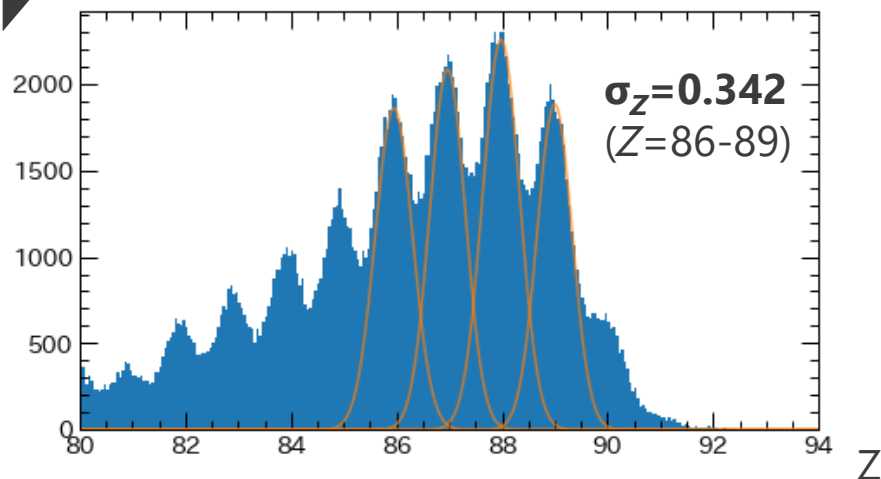
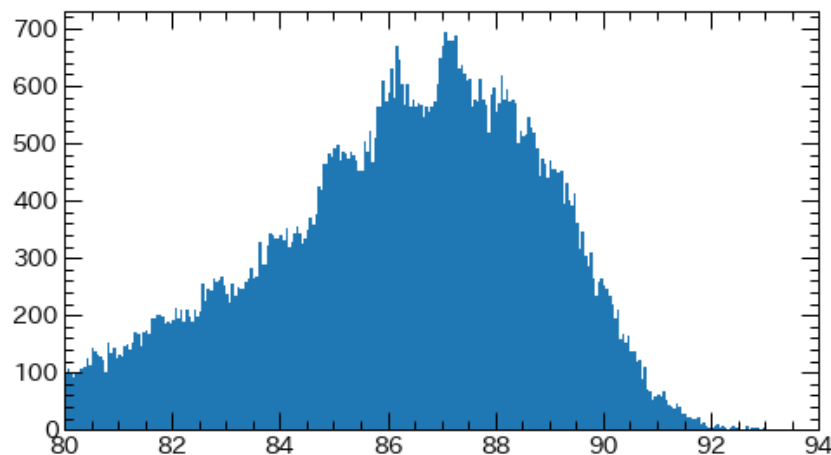


Particle ( $Z$ ) identification is difficult.



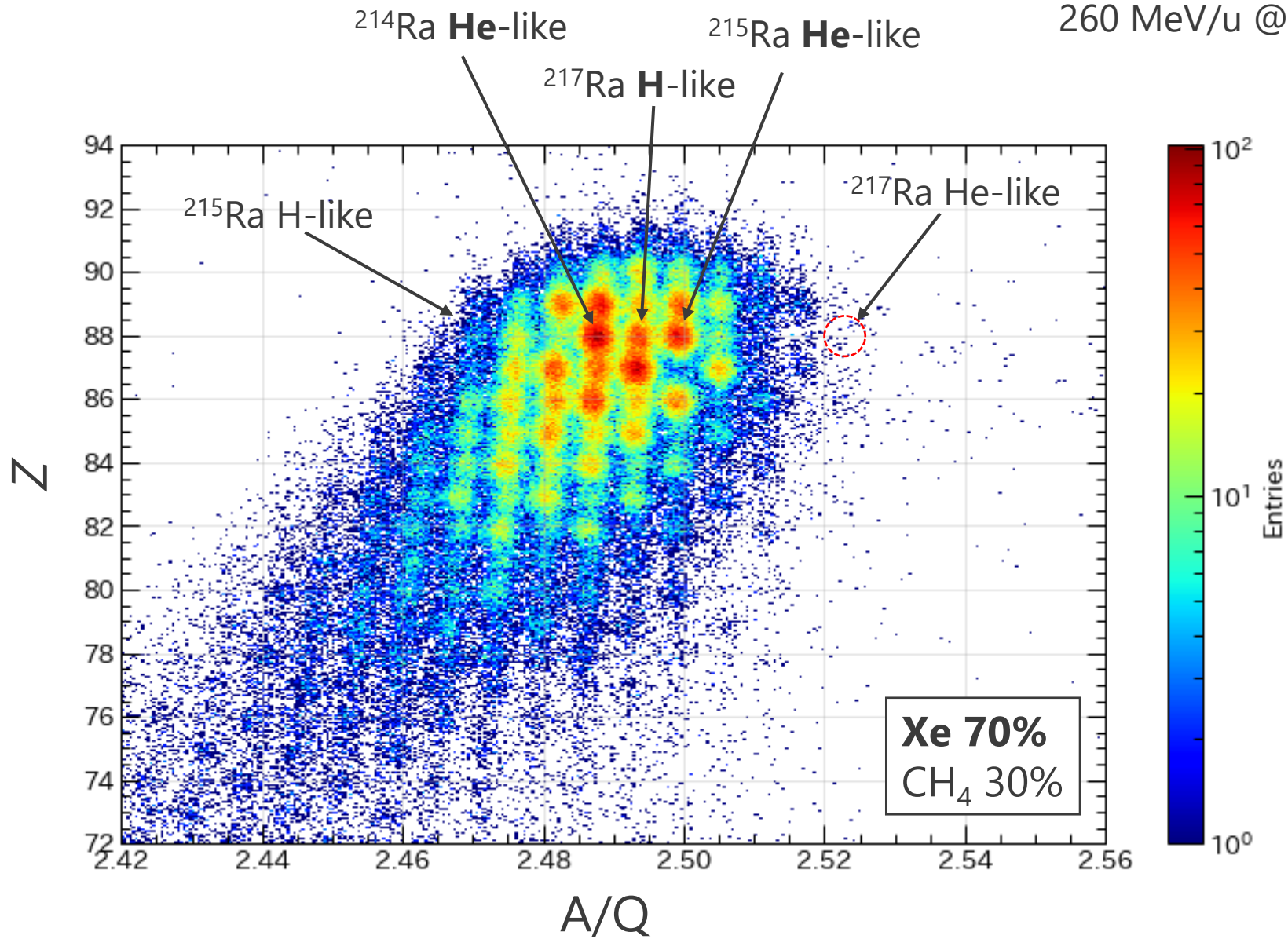
Clear peaks for each  $Z$

$A/Q$

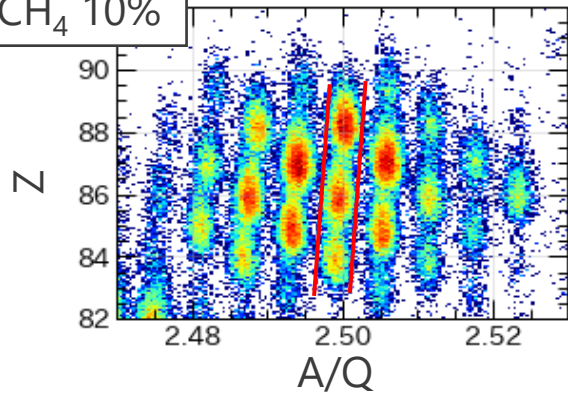


The particle ( $Z$ ) identification is possible with the Xe gas IC, even though the two charge states are transported.

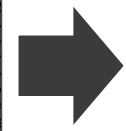
**Setting A**  
260 MeV/u @ Z=85



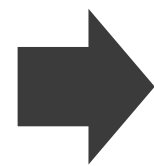
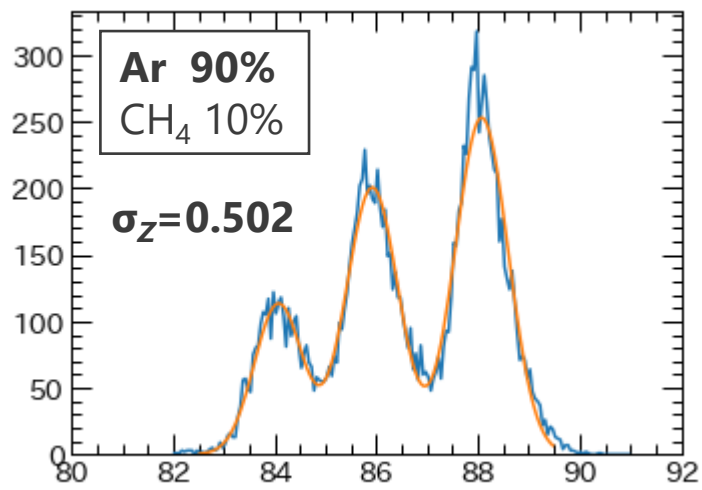
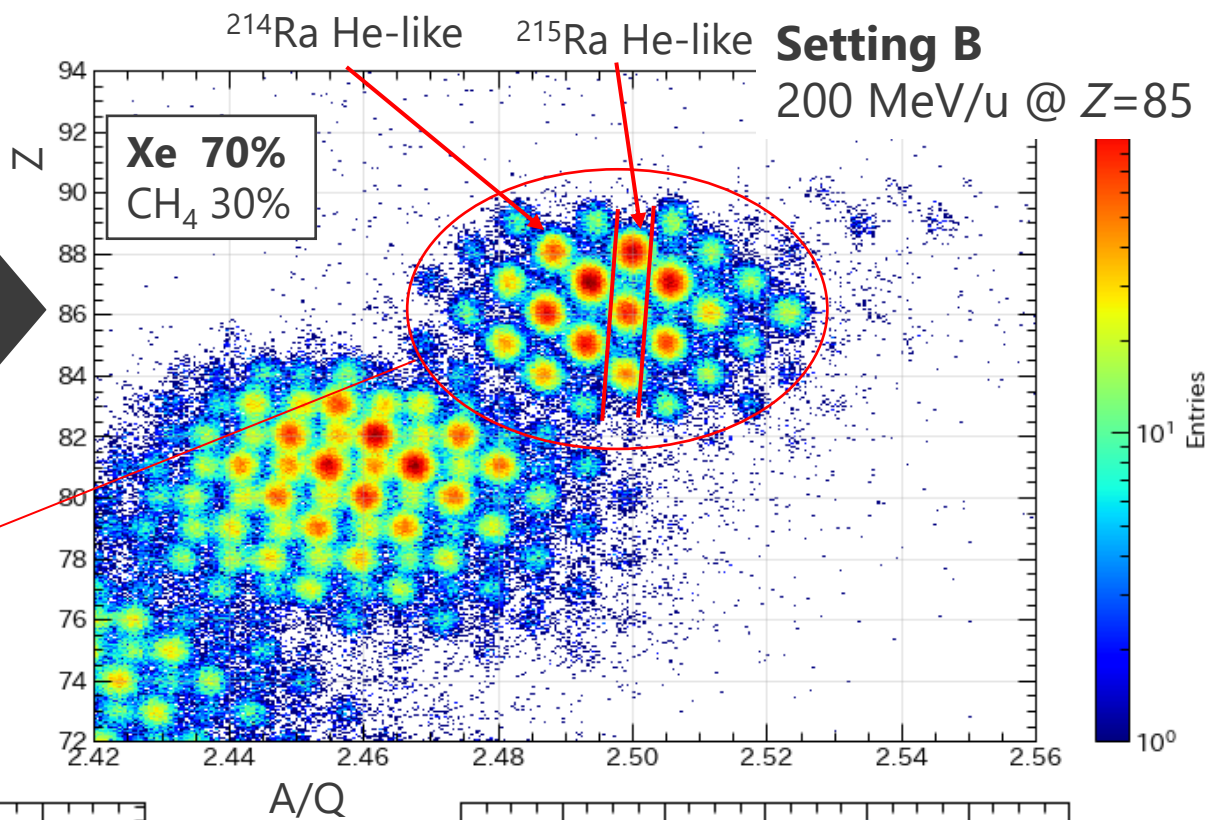
**Ar 90%**  
**CH<sub>4</sub> 10%**



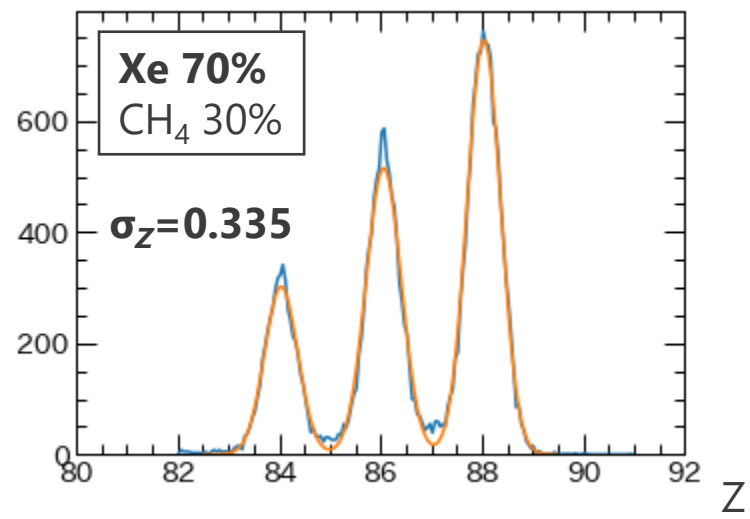
**He-like** is dominant in the group in the setting B, so PID is possible even with Ar gas IC.



**Xe 70%**  
**CH<sub>4</sub> 30%**



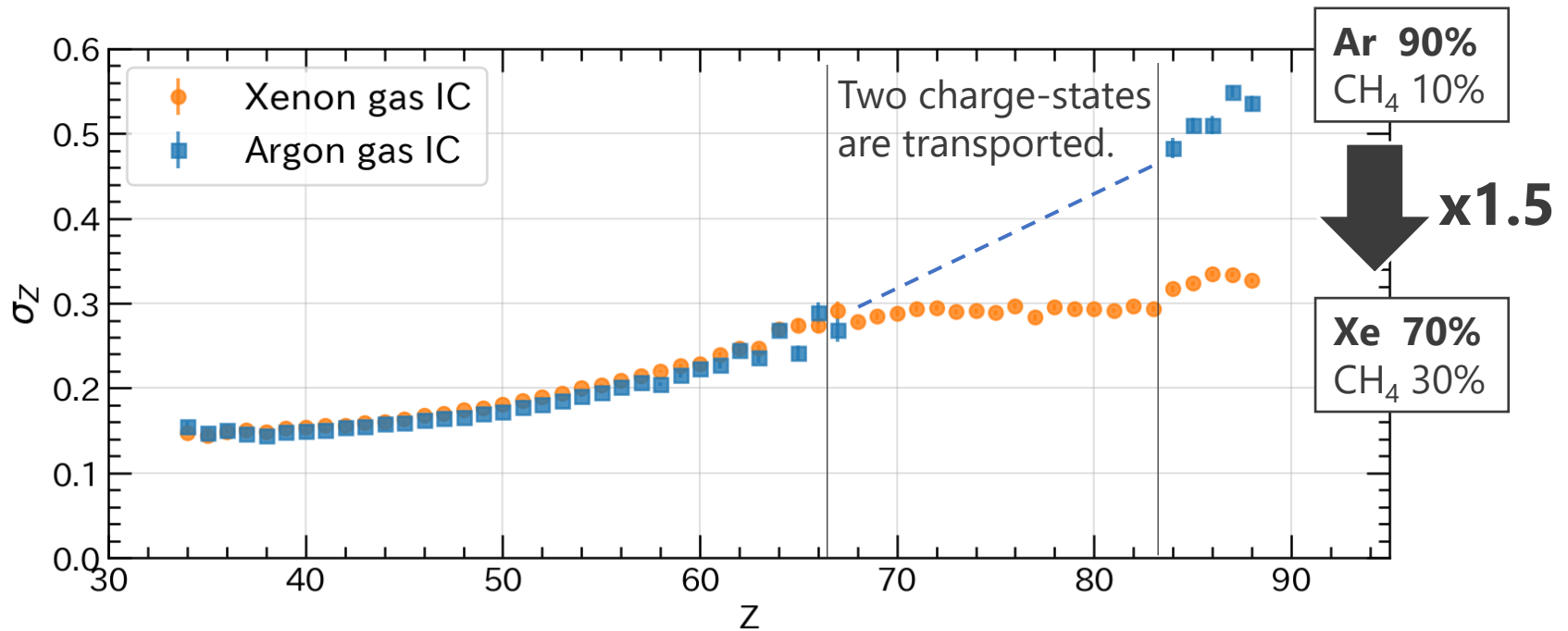
**x1.5**



Xe gas IC dramatically improved  $Z$  resolution in the high- $Z$  ( $Z > 80$ ) region.

# Z resolution of Xe and Ar gas IC

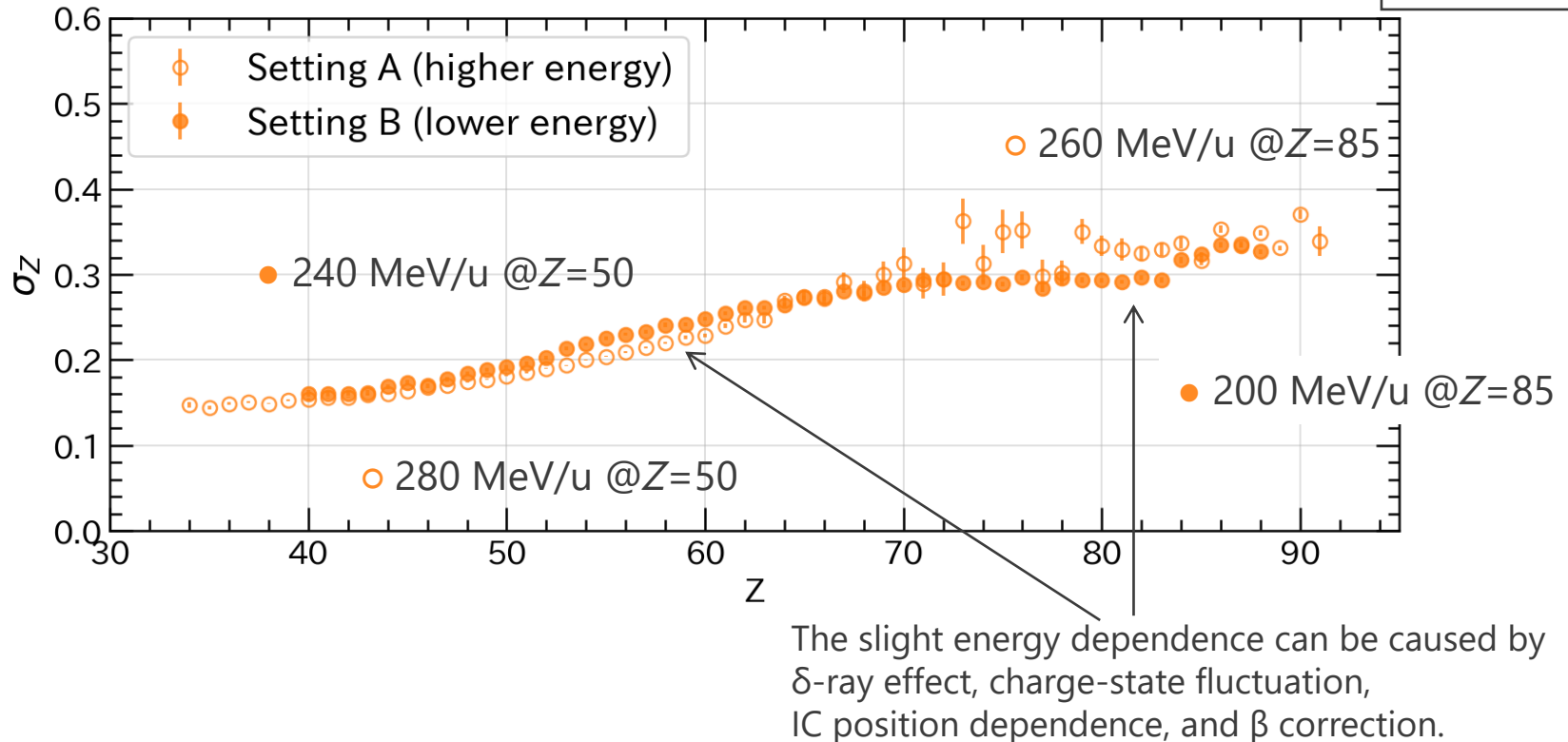
Setting B  
240 MeV/u @Z=50  
200 MeV/u @Z=85



Xe gas IC improves the Z resolution for  $Z > 70$ .

# Z resolution of Xe gas IC

**Xe 70%**  
**CH<sub>4</sub> 30%**



Almost no energy dependence was found in practical use.  
>3 $\sigma$  separation is achieved in the energy and Z regions.

# Summary

- Higher-Z beams will be provided with the  $^{238}\text{U}$  345 MeV/u primary beam at RIBF, and many experiments are waiting to be explored.
- A new **xenon-based gas** (Xe70%+CH<sub>4</sub>30%) **ionization chamber** (IC) has solved the PID problem at 200-300 MeV/u for the high-Z beam ( $Z > 70$ ).
  - **PID is possible** in the  **$Z > 70$**  region even when **different charge states** are transported.
  - Z resolution for  **$Z > 80$**  is improved by **1.5 times** compared to the P10 gas IC.
  - **$> 3\sigma$  separation** is achieved in the  **$Z = 30-90$  & 200-280 MeV/u** regions.
  - Energy loss of the Xe gas IC is slightly increased, but the advantages are much greater.